

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEINFORMATION DISCLOSURE
STATEMENTDocket Number
10191/1711Application Number
To Be AssignedFiling Date
HerewithExaminer
To Be AssignedArt Unit
To Be AssignedInvention Title
**DEVICE AND METHOD FOR HIGH-
RATE ETCHING A SUBSTRATE USING
A PLASMA ETCHING SYSTEM AND
DEVICE AND METHOD FOR IGNITING
A PLASMA AND ADJUSTING UPWARD
OR PULSING THE PLASMA POWER**Inventor(s)
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Assistant Commissioner for Patents
Washington, D.C. 20231

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following references to the attention of the Examiner. The references are listed on the attached modified PTO form 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

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